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# Dynamic RDS-on degradation analysis on power GaN HEMT by means of TCAD simulations and experimental measurement

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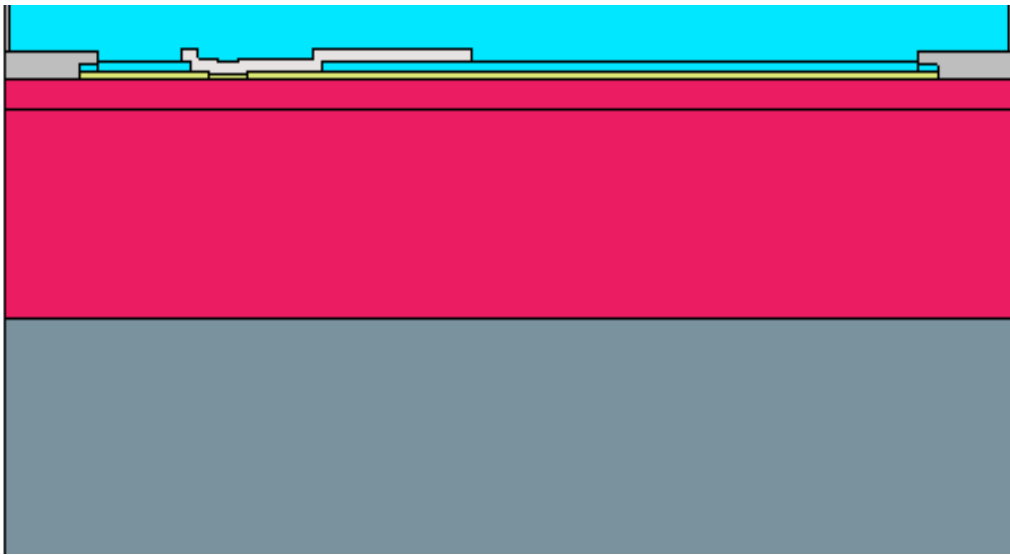
Paper presented during WOCSDICE - EXMATEC conference (May 2023 - Palermo, Italy)

GaN HEMT widely adopted for power application thanks to:

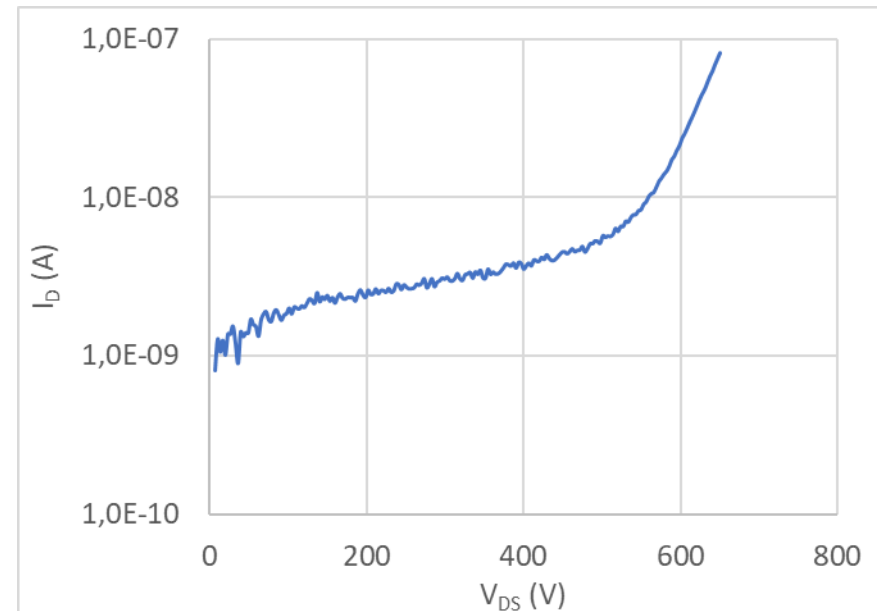
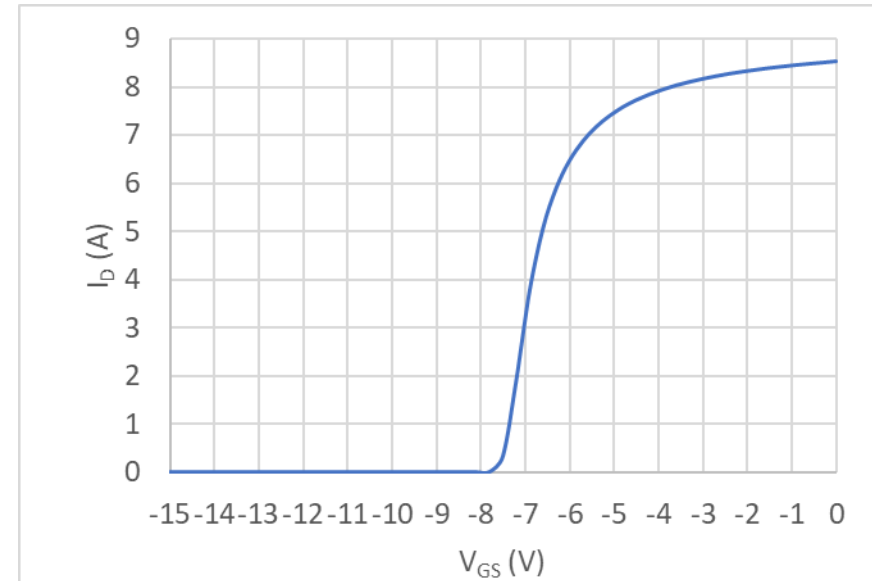
- ✓ high critical electric field → high voltage
- ✓ high 2DEG mobility and concentration → low  $R_{DS-on}$

However, GaN technology still present reliability issues:

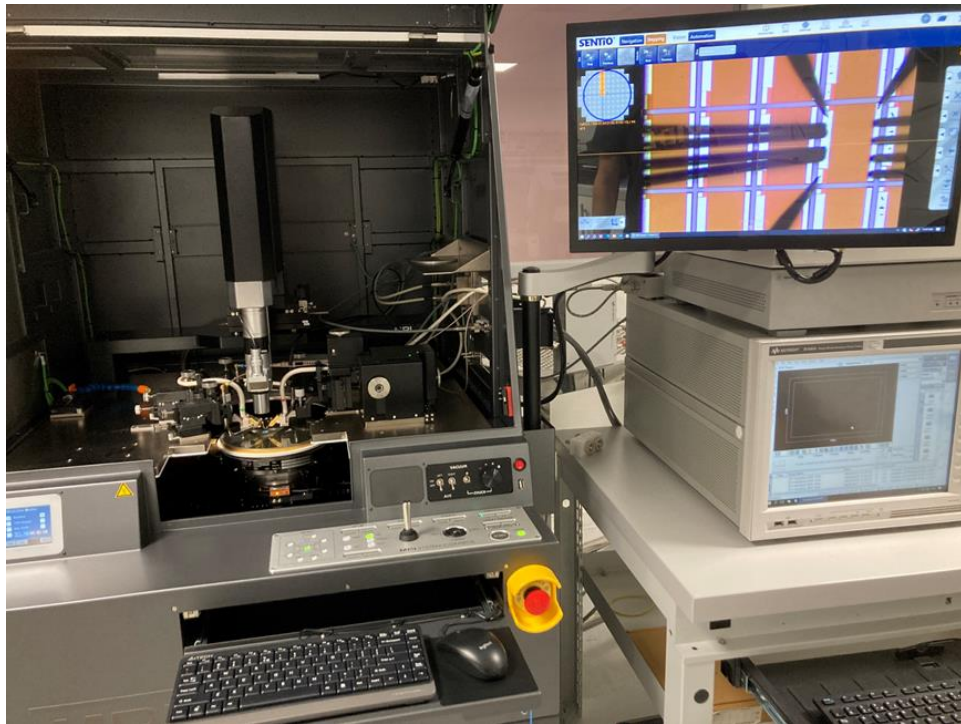
- ✓ For high voltage Fe or C is mandatory to limit leakage current  
→ creation of point defect traps related to these species
- ✓ Deep trap levels lead to current collapse effect → electrical performance degradation



- D-mode power HEMT for 650V applications
- Carbon doped buffer on Si substrate 8 (inches)
- Three field plates design



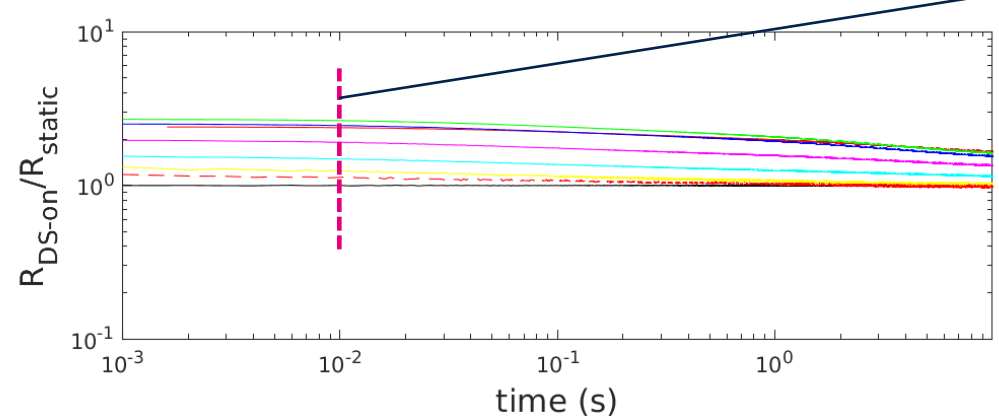
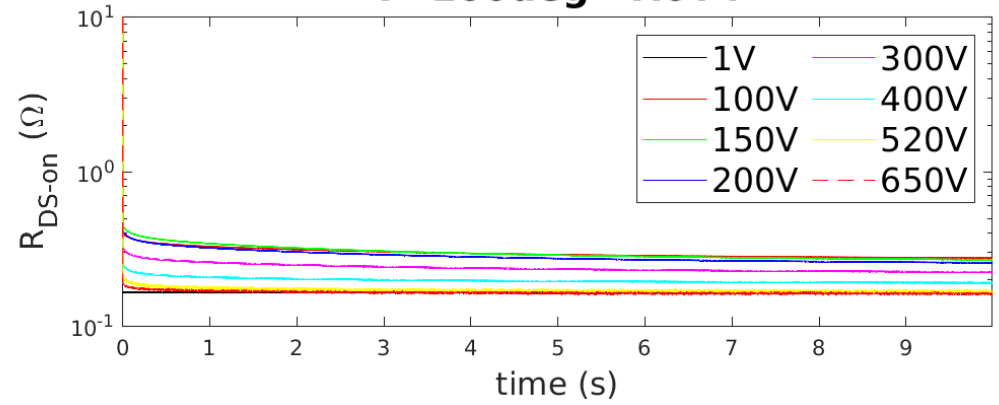




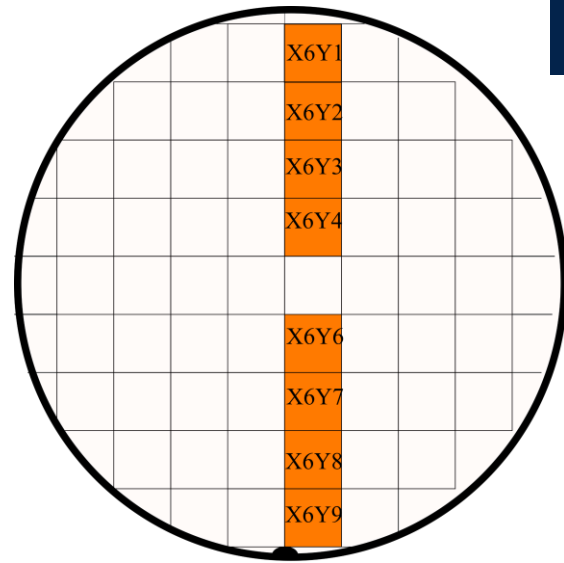
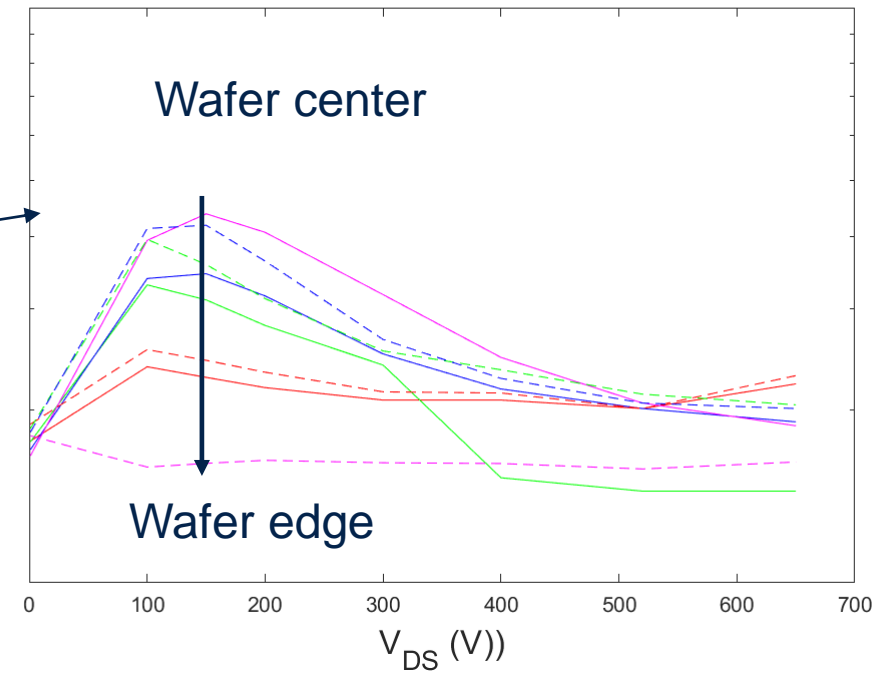
N1267A High Voltage / High Current Fast Switch

- Characterizations performed with B1505 associated to the and semi automatic probing station
- Current collapse option (high voltage / high current fast switch) to monitor  $R_{DS-on}$  variation after a stress
- Test performed on power transistors for different conditions:
  - Stress time: 1min
  - $V_{DS}$  (100 to 650V)
  - Temperatures between 80 and 120°C

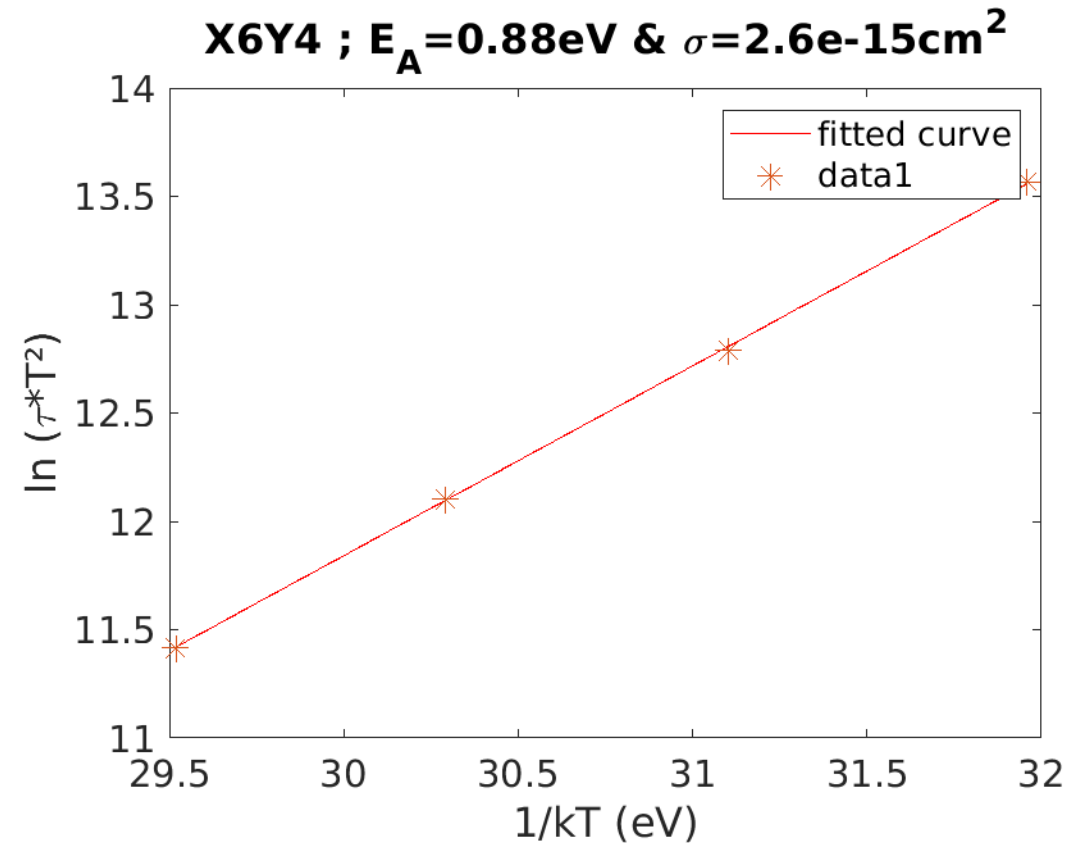
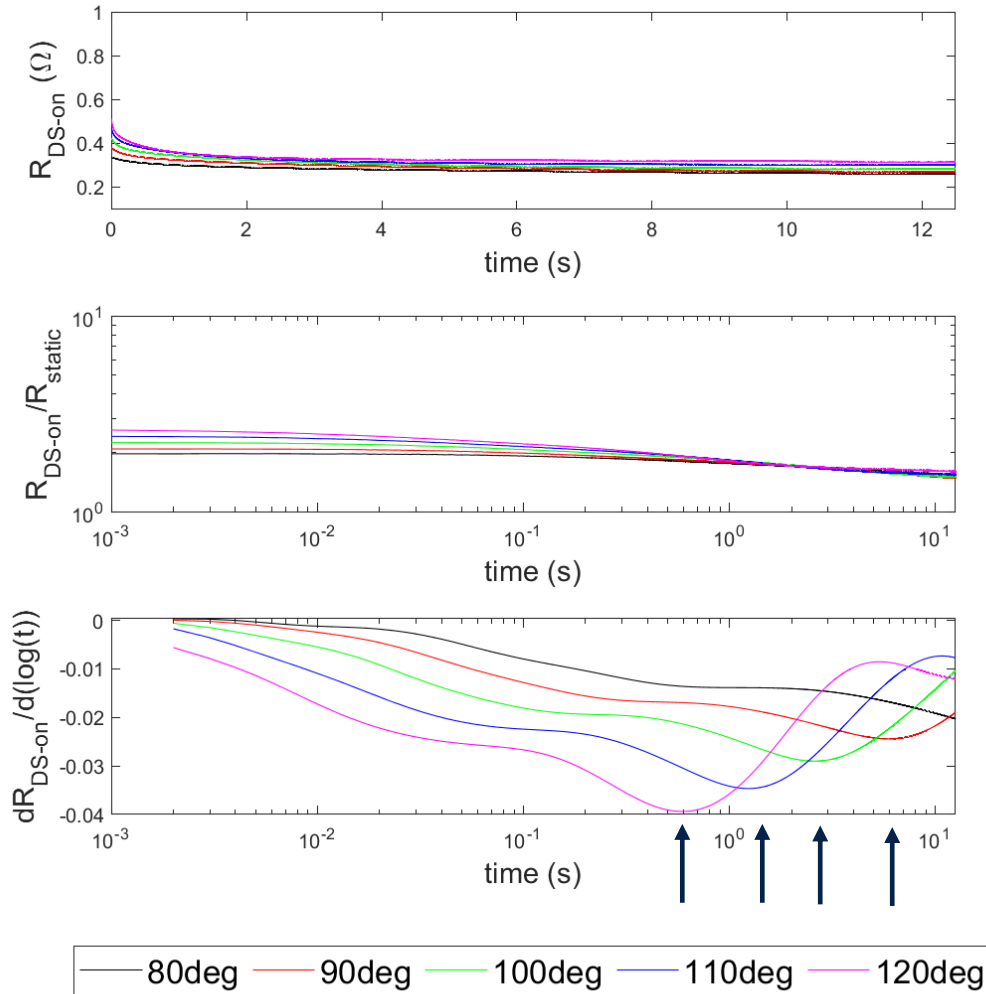
T=100deg - X6Y4



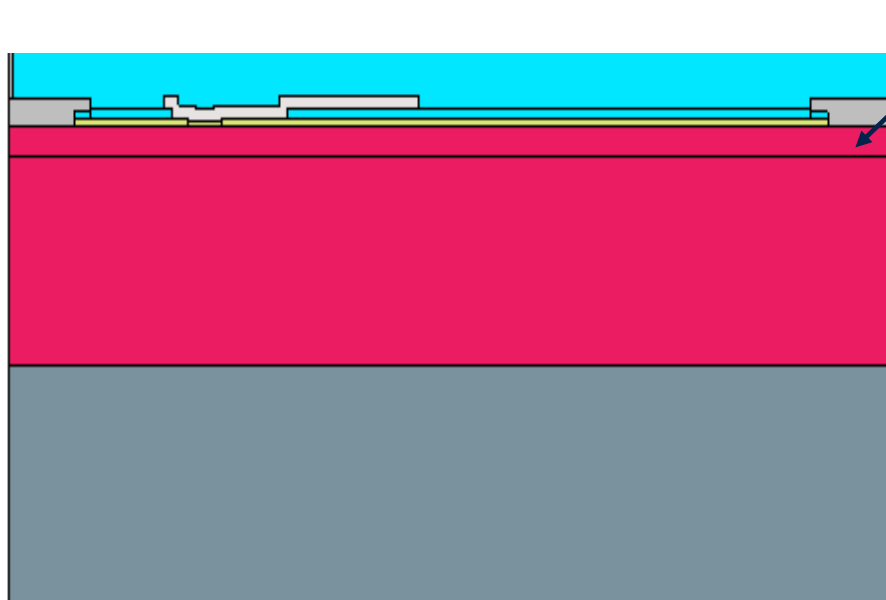
R<sub>DS-on</sub> vs V<sub>DS</sub> for T=100deg for t = 0.01s



- **Stress voltage effect:** Maximum of degradation for low V<sub>DS</sub> (100-150V), with a decrease at higher voltage
- **Center to edge effect:** Stronger degradation in the center of the wafer
- **Symmetry effect on wafer position:** same degradation at left and right from center

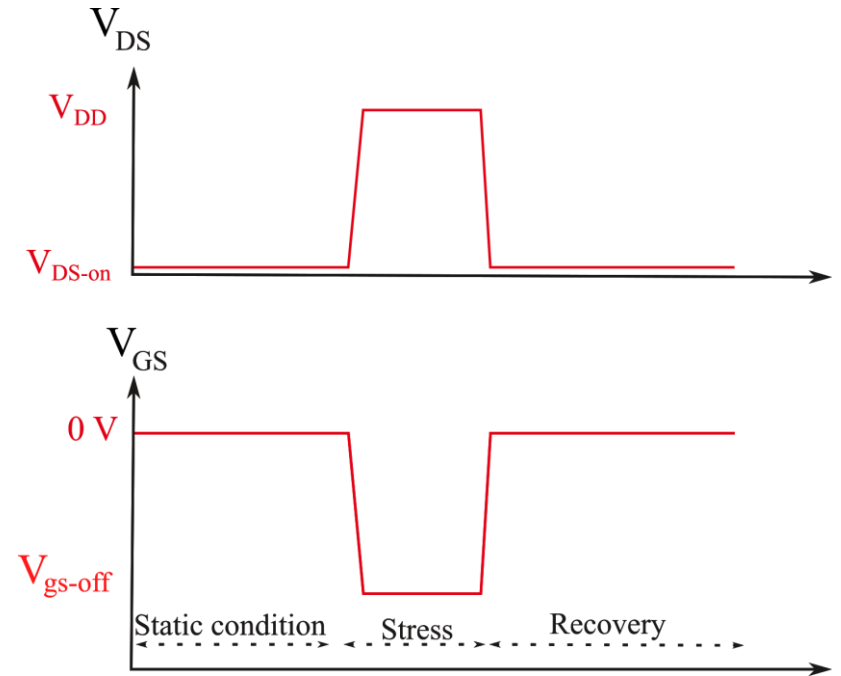
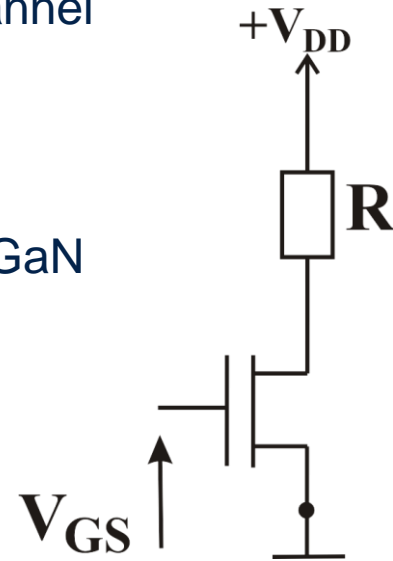


- Test repeated at different temperature for the most stressful condition: 100V in the center of the wafer
- Main trap time constant extracted from derivative of  $R_{DS-on}$
- Activation energy  $E_A=0.88\text{eV}$ : should be associated to carbon used in the epitaxy



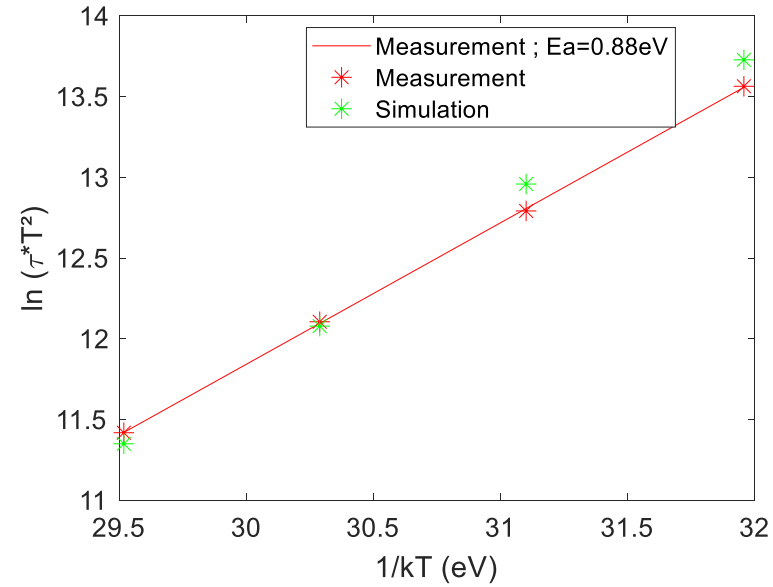
GaN channel

Carbon doped GaN buffer



- Mixed mode simulation
- Resistor value selected in order to limit the drain current to 1A (HEMT in linear mode)
- Pulsed source used for the gate with  $V_{gs-off} = -30V$  with very fast rise / fall time in the range of ns
- Buffer modeled by GaN associated to acceptors traps ( $E_T = 0.9 - E_V$ )
- Lower concentration of acceptors in the GaN channel, fully compensated by shallow donors
- General physical parameters:
  - Piezo-electric polarization based on Ambacher model
  - SRH recombination for traps
  - Mobility: temperature dependence due to phonon scattering & Canali for high field saturation

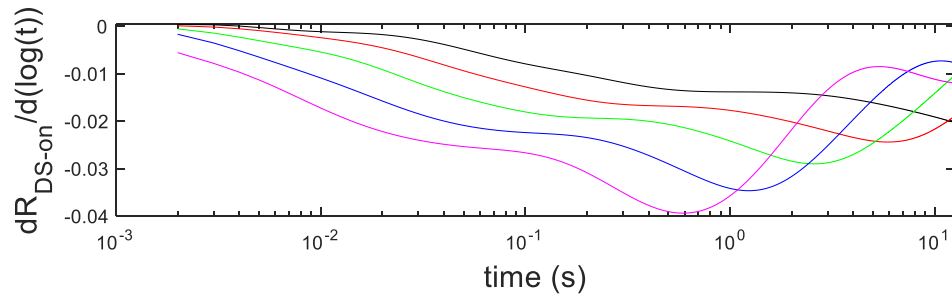
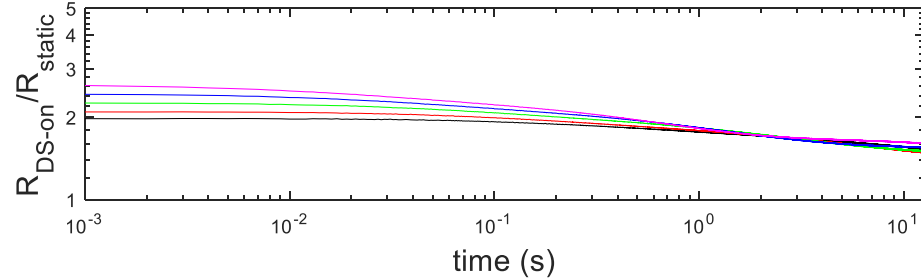
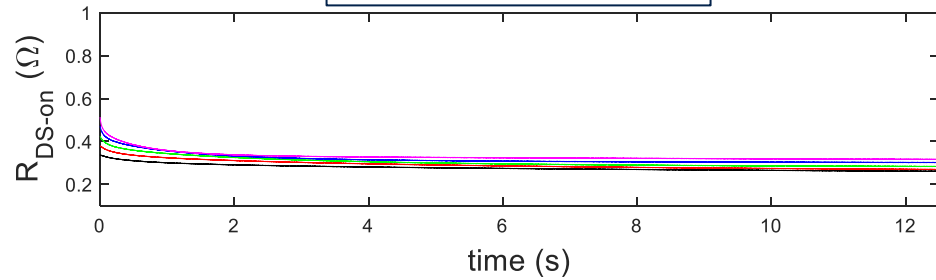
# Impact of temperature – tests on new wafer



## Stress conditions

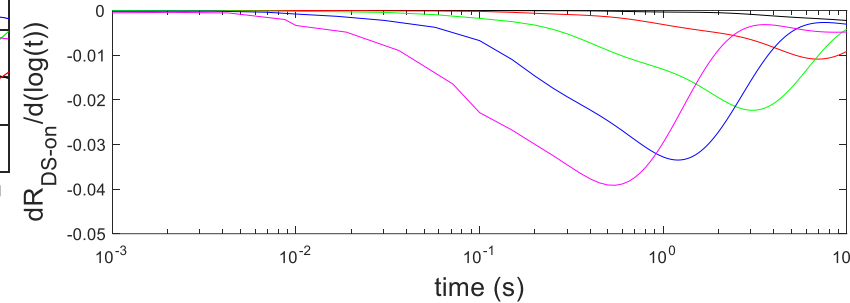
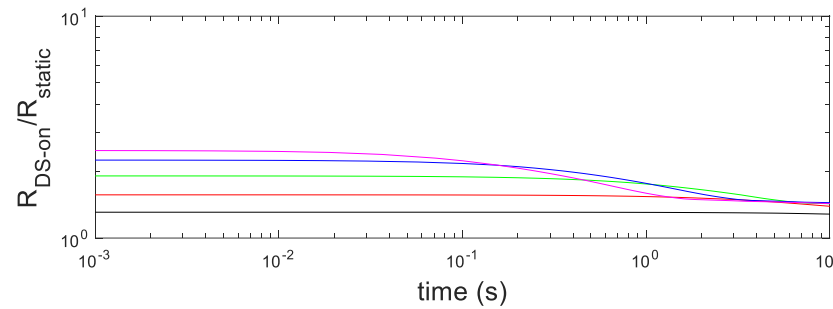
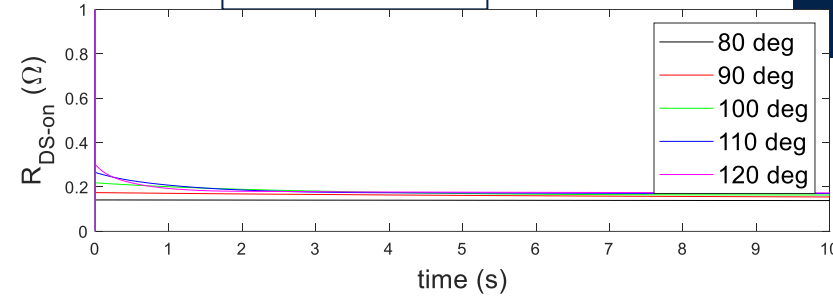
- $V_{DS}=100\text{V}$ ;  $V_{GS}=-30\text{V}$
- Stress duration: 1min

## Measurement



— 80deg — 90deg — 100deg — 110deg — 120deg

## Simulation



- Time constant dependent on trap cross section
- Same trends in terms of  $R_{DS-on}$  variation in simulation by adjusting the acceptor concentration
- Activation energy of  $\sim 0.9\text{eV}$  extracted from TCAD results



- Dynamic  $R_{DS-on}$  variation measured on D-mode HEMT for different condition highlighted the stronger degradation at low voltage
- Low voltage stress for different temperatures allowed us to extract an activation energy of 0.9eV that could be related to carbon
- TCAD simulation with traps of same activation energy in the GaN buffer could reproduce the same trend and allowed us to understand the electrical behavior
- Thanks to TCAD simulations, we could improve the transistor design to mitigate the  $R_{DS-on}$  degradation.

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